



Atty. Dkt. No. 064951-0204

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Robert BELLMAN et al.
Title: USING DEUTERATED SOURCE GASSES TO FABRICATE LOW LOSS
GeSiON SiON WAVEGUIDES
Appl. No.: 10/608,432
Filing Date: 06/30/2003
Examiner: Unassigned
Art Unit: 2874

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §1.56

Commissioner for Patents
PO Box 1450
Alexandria, Virginia 22313-1450

Sir:

Applicants submit herewith on Form PTO/SB/08 a listing of the documents cited by or submitted to the U.S. PTO in parent application Serial No. 09/693,445, filed October 20, 2000. As provided in 37 CFR §1.98(d), copies of the documents are not being provided since they were previously submitted to the United States Patent & Trademark Office in the above-identified parent application.

The submission of any document herewith, which is not a statutory bar, is not intended as an admission that such document constitutes prior art against the claims of the present application or that such document is considered material to patentability as defined in 37 CFR §1.56(b). Applicants do not waive any rights to take any action which would be appropriate to antedate or otherwise remove as a competent reference any document which is determined to be a *prima facie* art reference against the claims of the present application.

TIMING OF THE DISCLOSURE

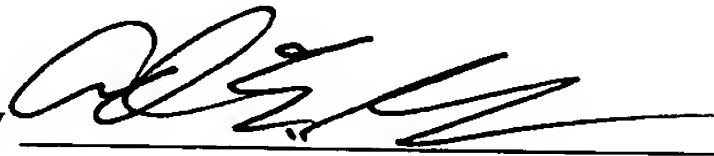
The listed documents are being submitted in compliance with 37 CFR §1.97(b), before the mailing date of the first Office Action on the merits.

Applicants respectfully request that the listed documents be considered by the Examiner and be made of record in the present application and that an initialed copy of Form PTO/SB/08 be returned in accordance with MPEP §609.

The Commissioner is hereby authorized to charge any additional fees which may be required regarding this application under 37 CFR §§ 1.16-1.17, or credit any overpayment, to Deposit Account No. 19-0741. Should no proper payment be enclosed herewith, as by a check being in the wrong amount, unsigned, post-dated, otherwise improper or informal or even entirely missing, the Commissioner is authorized to charge the unpaid amount to Deposit Account No. 19-0741.

Respectfully submitted,

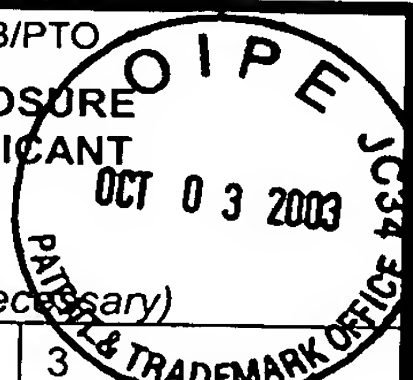
Date October 3, 2003

By 

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Substitute for form 1449B/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Application Number	10/608,432
				Filing Date	06/30/2003
				First Named Inventor	Robert BELLMAN
				Group Art Unit	2874
				Examiner Name	Unassigned
Sheet 1 of 3				Attorney Docket Number	064951-0204

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
	A1	4,962,065		BROWN et al.	10-09-1990	
	A2	5,062,680		IMAMURA et al.	11-05-1991	
	A3	5,264,724	A	BROWN et al.	1-23-1993	
	A4	5,343,544	A	BOYD et al.	08-30-1994	
	A5	5,694,513	A	OKANIWA	12-02-1997	
	A6	5,979,188	A	OJHA	11-09-1999	
	A7	5,972,765	A	CLARK et al.	11-26-1999	
	A8	6,077,791	A	DeTAR	06-20-2000	
	A9	6,229,949	B1	IDO et al.	05-08-2001	
	A10	6,341,190	B1	SUMMERSGILL et al.	01-22-2002	
	A11	6,393,185	B1	DEACON	05-21-2002	
	A12	6,499,318	B1	LEMAIRE et al.	12-31-2002	

FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Documents	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Office ³	Number ⁴	Kind Code ⁵ (if known)				
	A13	WO	01/64594	A1	INTERNATIONAL BUSINESS MACHINES CORPORATION	09-07-2001		
	A14	JP	09-078244		CANON INC.	03-25-1997		
	A15	EP	0 673 895	A2	AT&T CORP.	09-27-1995		

Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

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		Examiner Name	Unassigned
		Attorney Docket Number	064951-0204

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ⁶
	A16	ARNOLDBIK et al., "Dynamic Behavior of Hydrogen in Silicon Nitride and Oxynitride Films Made by Low-Pressure Chemical Vapor Deposition", The American Physical Society, Physical Review B, Vol. 48, No. 8, Aug. 15, 1993, pp. 5444-5456	
	A17	BOGATYRJOV et al., "Passive Selective Filter for Flattening the Erbium-Doped Fibre Amplifier Gain Spectrum Based on a Feature of the Silicon Oxynitride Fibre Absorption Spectrum", Electronics Letters, Vol. 31, No. 1, Jan. 5, 1995, pp. 61-62	
	A18	BONA et al., "Wavelength Division Multiplexed Add/Drop Ring Technology in Corporate Backbone Networks", Optical Engineering, Vol. 37, No. 12, Dec. 1998, pp. 3218-3228	
	A19	BOSSEBOEUF and BOUCHIER, "Mechanisms of Reactive Ion-Beam Sputtering of Silicon Nitride in Presence of ¹⁵ N- or D-Labeled Ammonia," J. Electrochem. Society, Vol. 133, No. 4, April 1986, pp. 810-816	
	A20	CAVALLARI et al., "Plasma Processing for Silicon Oxynitride Films", J. Electrochem. Soc., Vol. 134, No. 5, May 1987, pp. 1265-1270	
	A21	DENISSE et al., "Annealing of Plasma Silicon Oxynitride Films", J. Appl. Phys., Vol. 60, No. 7, Oct. 1, 1986, pp 2543-2547	
	A22	GERMAN et al., "Silicon-oxynitride Layers for Optical Waveguide Applications," <u>Electrochemical Society Proceedings</u> , Vol. 99-6	
	A23	HABRAKEN et al., "Hydrogen in low-pressure chemical-vapor-deposited silicon (oxy)nitride films," <u>J. Appl. Phys.</u> , January 15, 1986, Vol. 59, No. 2	
	A24	HABRAKEN et al., "Hydrogen in Low-Pressure Chemical-Vapor-Deposited Silicon (Oxy)Nitride Films", J. Appl. Phys. Vol. 59, No. 2, Jan. 15, 1986, pp. 447-453	
	A25	HE et al., "Hydrogen Behavior in PECVD Nitride by SiH ₄ & ND ₃ During RTA," Mat. Res. Soc. Symp. Proc., Vol. 424, Apr. 8-12, 1996, San Francisco, CA pp. 109-114	
	A26	HUBNER, "Strong Bragg Gratings Induced with 248 nm Light in Buried Silicon Oxynitride Waveguides," XP-000987165	
	A27	OHRING, "The Materials Science of Thin Films", 1992, pp. 181-184	
	A28	SPEAKMAN et al., "Characterization of PECVD Deposited Silicon Oxynitride Thin Films", Vacuum, Vol. 38, No. 3, 1988, pp. 183-188	

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